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I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail, in an envelope addressed to: MS Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below.

Dated: October 21, 2004

Signature:

Docket No.: 30205/39509

Art Unit: 1752

Examiner: Amanda C. Walke

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Cheol-Kyu Bok et al.

Application No.: 10/722,815

Filed: November 26, 2003

For: OVERCOATING COMPOSITION FOR

PHOTORESIST AND METHOD FOR

FORMING PHOTORESIST PATTERN USING

THE SAME

AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION

MS Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

Please enter the following amendment in the above-referenced patent application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments in support of the allowability of this application begin on page 6 of this paper.